

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/616,623	LU ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,608,645	03-1997	Spyrou, Athanasius W.	716/6
	B	US-5,835,751	11-1998	Chen et al.	716/16
	C	US-6,311,313	10-2001	Camporese et al.	716/6
	D	US-2004/0123259	06-2004	You et al.	716/006
	E	US-5,452,239	09-1995	Dai et al.	703/19
	F	US-5,649,167	07-1997	Chen et al.	703/23
	G	US-5,715,172	02-1998	Tzeng, Ping-San	716/6
	H	US-6,205,571	03-2001	Camporese et al.	716/2
	I	US-6,266,803	07-2001	Scherer et al.	716/12
	J	US-6,618,816	09-2003	Ido et al.	713/503
	K	US-6,665,845	12-2003	Aingaran et al.	716/5
	L	US-6,684,373	01-2004	Bodine et al.	716/6
	M	US-6,799,308	09-2004	You et al.	716/6

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 09218888 A	08-1997	Japan	TAWADA, SHIGEYOSHI	G06F 17/50
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	NA9402189, "Process-Variation-Tolerant Zero Skew Clock Routing", IBM Technical Disclosure Bulletin, Vol. 37, No. 2A, February 1994, pp. 189-198 (10 pages).
	V	Feehrer, "The Effect of Propagation Delay Uncertainty on the Speed of Time-of-Flight Digital Optoelectronic Circuits", Journal of Lightwave Technology, Vol. 14, No. 12, pp. 2698-2713, December 1996.
	W	Pullela et al., "Moment-Sensitivity-Based Wire Sizing for Skew Reduction in On-Chip Clock Nets", IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems, Vol. 16, No. 2, pp. 210-215, February 1997.
	X	Balatsos et al., "Low-Skew Clock Generator with Dynamic Impedance and Delay Matching", IEEE International Solid-State Circuits Conference, 15 February 1999, pp. 182-183.

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

<b>Notice of References Cited</b>	Application/Control No.	Applicant(s)/Patent Under Reexamination	
	10/616,623	LU ET AL.	
	Examiner	Art Unit	
	Phallaka Kik	2825	Page 2 of 4

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,836,874	12-2004	Batchelor et al.	716/6
	B	US-6,880,141	04-2005	Tetelbaum, Alexander	716/6
	C	US-6,910,194	06-2005	Mielke et al.	716/6
	D	US-6,941,532	09-2005	Haritsa et al.	716/6
	E	US-6,954,915	10-2005	Batchelor, Dennis B.	716/6
	F	US-2003/0074642	04-2003	Haritsa et al.	716/6
	G	US-2003/0074643	04-2003	Schmitt et al.	716/6
	H	US-2003/0121013	06-2003	Moon et al.	716/6
	I	US-2004/0003360	01-2004	Batchelor et al.	716/6
	J	US-2004/0015801	01-2004	Mielke et al.	716/6
	K	US-2004/0025129	02-2004	Batchelor, Dennis B.	716/6
	L	US-2004/0107408	06-2004	Sano et al.	716/002
	M	US-2004/0268279	12-2004	Oleksinski et al.	716/006

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
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	W	
	X	

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<b>Notice of References Cited</b>	Application/Control No.	Applicant(s)/Patent Under Reexamination	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4,924,430	05-1990	Zasio et al.	716/6
	B	US-5,258,660	11-1993	Nelson et al.	327/141
	C	US-5,298,866	03-1994	Kaplinsky, Cecil H.	327/261
	D	US-5,414,381	05-1995	Nelson et al.	327/262
	E	US-5,467,040	11-1995	Nelson et al.	327/276
	F	US-5,852,640	12-1998	Kliza et al.	375/356
	G	US-5,936,867	08-1999	Ashuri, Roni	716/6
	H	US-6,219,384	04-2001	Kliza et al.	375/258
	I	US-6,324,671	11-2001	Ratzel et al.	716/1
	J	US-6,518,788	02-2003	Kasahara, Fumio	326/46
	K	US-6,536,022	03-2003	Aingaran et al.	716/5
	L	US-6,606,736	08-2003	Kobayashi et al.	716/10
	M	US-6,578,182	06-2003	Kurokawa et al.	716/6

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

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		10/616,623	LU ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,651,224	11-2003	Sano et al.	716/2
	B	US-2002/0029361	03-2002	Kasahara, Fumio	714/726
	C	US-2002/0073389	06-2002	Elboim et al.	716/6
	D	US-2002/0104035	08-2002	Burns et al.	713/500
	E	US-2002/0161947	10-2002	Ikeda et al.	710/38
	F	US-2003/0070151	04-2003	Kurokawa et al.	716/6
	G	US-2003/0115493	06-2003	Wong et al.	713/322
	H	US-2003/0159118	08-2003	Lindkvist, Hans	716/5
	I	US-2003/0177464	09-2003	Takechi et al.	716/10
	J	US-2003/0212971	11-2003	Rodgers et al.	716/6
	K	US-2005/0132313	06-2005	Lindkvist, Hans	716/006
	L	US-6,090,150	07-2000	Tawada, Shigeyoshi	703/19
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

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*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
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